



# *Article* **Bottom-Up (Cu, Ag, Au)/Al2O3/Bi2Te<sup>3</sup> Assembled Thermoelectric Heterostructures**

**Zhenhua Wu** <sup>1[,](https://orcid.org/0000-0002-5527-0310)2,3</sup> $\bullet$ , Shuai Zhang<sup>1,2,3</sup>, Zekun Liu<sup>1,2,3</sup>, Cheng Lu<sup>1,2,3</sup> and Zhiyu Hu<sup>1,\*</sup>

- <sup>1</sup> National Key Laboratory of Science and Technology on Micro-Nano Fabrication, Shanghai Jiao Tong University, Shanghai 200240, China; wuzhenhua@sjtu.edu.cn (Z.W.); zhangs0521@sjtu.edu.cn (S.Z.); liuzekun@sjtu.edu.cn (Z.L.); lucheng\_2020@sjtu.edu.cn (C.L.)
- <sup>2</sup> Department of Micro/Nano-Electronics, Shanghai Jiao Tong University, Shanghai 200240, China
- 3 Institute of Nano-Micro Energy, Shanghai Jiao Tong University, Shanghai 200240, China
- **\*** Correspondence: zhiyuhu@sjtu.edu.cn

**Abstract:** The interface affects the transmission behavior of electrons and phonons, which in turn determines the performance of thermoelectric materials. In this paper, metals (Cu, Ag, Au)/Al<sub>2</sub>O<sub>3</sub>/ Bi<sub>2</sub>Te<sub>3</sub> heterostructures have been fabricated from bottom to up to optimize the thermoelectric power factor. The introducing metals can be alloyed with  $Bi<sub>2</sub>Te<sub>3</sub>$  or form interstitials or dopants to adjust the carrier concentration and mobility. In addition, the metal-semiconductor interface as well as the metal-insulator-semiconductor interface constructed by the introduced metal and  $A<sub>1</sub>O<sub>3</sub>$  would further participate in the regulation of the carrier transport process. By adjusting the metal and oxide layer, it is possible to realize the simultaneous optimization of electric conductivity and Seebeck coefficient. This work will enable the optimal and novel design of heterostructures for thermoelectric materials with further improved performance.

**Keywords:** thermoelectric; Bi2Te<sup>3</sup> ; heterostructure; interface; metal; oxide

## **1. Introduction**

Thermoelectric technology can convert heat to electricity freely. The thermoelectric (TE) efficiency is normally evaluated by the dimensionless figure of merit  $ZT = S^2 \sigma T / \kappa$  $(\kappa = \kappa_e + \kappa_l)$ , where *S*,  $\sigma$ ,  $\kappa$ ,  $\kappa_e$ ,  $\kappa_l$ , and *T* are the Seebeck coefficient, electrical conductivity, thermal conductivity, electronic thermal conductivity, lattice thermal conductivity, and absolute temperature, respectively [\[1\]](#page-5-0). One strategy to improve the thermoelectric performance is fabricating nanostructures such as pores [\[2](#page-5-1)[,3\]](#page-5-2) or nanograins [\[4,](#page-5-3)[5\]](#page-5-4), which could strongly scatter phonons and thereby reducing the lattice thermal conductivity. However, little room remains for further reducing κ. On the one hand, the contribution of electrons to thermal conductivity is unavoidable due to Wiedemann-Franz law. On the other hand, the lattice thermal conductivity cannot be lower than the amorphous state. For  $Bi_2Te_3$  system with excellent thermoelectric properties near room temperature, the lattice thermal conductivity has been approached to lower as ~0.3 W·m<sup>-1</sup>·K<sup>-1</sup>, which is the limit value predicted by Cahill model [\[6,](#page-5-5)[7\]](#page-5-6). Further improvements in the *ZT* could be relied on decoupling *S* and  $\sigma$  to improve the power factor ( $PF = S^2 \sigma$ ).

Compared with its bulk counterparts, nanostructured  $Bi_2Te_3$  film provides promising possibilities for enhanced TE properties and potential applications in micro/nanoelectromechanical systems (MEMS/NEMS) TE device [\[8\]](#page-5-7). The thermoelectric performance of Bi2Te<sup>3</sup> can be optimized by adjusting the (00*l*) orientation [\[9](#page-5-8)[,10\]](#page-6-0), pores [\[9,](#page-5-8)[11\]](#page-6-1), nanosheet boundary  $[12,13]$  $[12,13]$ , and the intrinsic defects  $[14,15]$  $[14,15]$ . In addition, constructing a heterogeneous interface is also one of the effective methods to optimize the thermoelectric performance. The heterogeneous interface can filter low-energy carriers that contribute negative to the Seebeck coefficient through the interface barrier and thus the thermoelectric power factor will be enhanced [\[16\]](#page-6-6). Meanwhile, the interface could also scatter phonons to reduce



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the lattice thermal conductivity, and finally the *ZT* value of the material will be further improved [\[1\]](#page-5-0). Experimentally, metal/semi-metal or carbon had been introduced in Bi<sub>2</sub>Te<sub>3</sub> to build heterostructures (such as  $Bi_2Te_3/Ag$  [12,17],  $Bi_2Te_3/Cu$  [12,18]  $Bi_2Te_3/Cd$  [19],  $Bi_2Te_3/Te$  [20],  $Bi_2Te_3/carbon$  nanotube [10,21]) especially by solution or sintering method to further enhanced the TE properties. Oxide layer was also introduced into the Ag/Sb<sub>2</sub>Te<sub>3</sub> system by atomic layer deposition, and the filtering effect of the corresponding interface on low-energy carriers was discussed [6]. In this paper, group IB metals (M = Cu, Ag, Au) and  $\text{Al}_2\text{O}_3$  interfaces were systematically introduced into  $\text{Bi}_2\text{Te}_3$  film to modulate the carrier behavior and thus enhance the thermoelectric power factor. Incidentally, the introduced interface can also scatter phonons to reduce the thermal conductivity of the lattice, which is beneficial to improve the  $ZT$  value.

reduce the thermal conductivity of the lattice, which is beneficial to improve the *ZT* val-

## **2. Materials and Methods** is marked as B. Cu/Bi2Te3, Ag/Bi2Te3, and Au/Bi2Te3 samples are marked as CB, SB, and

Group IB metal M (M = Cu, Ag, Au) with a thickness of 6~10 nm was pre-deposited on SiO $_2$ /Si substrates by an e-beam evaporation system. Using Al $_2$ O $_3$  targets, Al $_2$ O $_3$  layer with a thickness of ~3 nm was first selectively sputtered on the pre-deposited metal. Then,  ${\rm Bi}_2{\rm Te}_3$ films with a thickness of about 300 nm were sputtered. The base vacuum of the sputtering chamber was  $5E^{-3}$  Pa and the working pressure was 0.26 Pa. The substrate was rotated at a speed of 20 rpm to ensure the uniformity of the sputtered film. The  $\rm Al_2O_3$  sputtered at 100 W and  $Bi_2Te_3$  sputtered at 50 W were both in a radio frequency (RF) mode. The purity of all source materials is 99.99%. The sample preparation is illustrated in Figure [1a](#page-1-0). For the convenience of description in the following part, pure  $Bi_2Te_3$  is marked as B. Cu/ $Bi_2Te_3$ , Ag/Bi<sub>2</sub>Te<sub>3</sub>, and Au/Bi<sub>2</sub>Te<sub>3</sub> samples are marked as CB, SB, and GB, respectively. Cu/Al<sub>2</sub>O<sub>3</sub>/  $Bi_2Te_3$ ,  $Ag/Al_2O_3/Bi_2Te_3$ , and  $Au/Al_2O_3/Bi_2Te_3$  are marked as CAB, SAB, and GAB, respectively.  $e^{\frac{1}{2}}$ 

<span id="page-1-0"></span>

**Figure 1.** (**a**) Film preparation process. SEM image of (**b**) Cu, (**c**) Ag and (**d**) Au surface. AFM image of (**e**) Ag and (**f**) Ag/  $\text{Al}_2\text{O}_3$ . (**g**) AFM step profiler of Ag and Ag/ $\text{Al}_2\text{O}_3$ .

The surface morphology, cross section, composition, and thickness of films were characterized by atomic force microscope (AFM, Multimode Nanoscope IIIa), scanning electron microscopy with energy dispersive spectrometer (SEM-EDS, Zeiss Ultra Plus) and surface profiler (KLA-Tencor P7). The structures of the films were characterized by X-ray diffraction (XRD, D8 Advance) with a Cu Kα radiation (λ = 1.5406Å) in conventional θ–2θ mode from 10–80 $\degree$  at a sweep rate of  $4\degree$ /min. Electrical transport of film was obtained by Hall measurement (model: MMR) with a Van der Pauw pattern and averaged by three measurements. The contact effect and other additional effect including heating effect of current and asymmetric effect of probing electrodes can be exclude in this current reversal method with four-probe configuration. The Seebeck coefficient was evaluated by a home-built system as reported in detail in our previous study [\[22\]](#page-6-12).

# **3. Results and Discussion 3. Results and Discussion**

#### *3.1. Heterostructure Characterization 3.1. Heterostructure Characterization*

The pre-deposited metal presents as discontinuous particles as shown in Figure 1b–d. The pre-deposited metal presents as discontinuous particles as shown in Figu[re](#page-1-0) 1b– The height of Ag is about 10 nm, while the height of Cu and Au is about 6–7 nm as d. The height of Ag is about 10 nm, while the height of Cu and Au is about 6–7nm as shown in Figures [1](#page-1-0) and S1. After sputtering  $\text{Al}_2\text{O}_3$ , the total height of the metal particles increased by ~3 nm. Interestingly,  $\text{Al}_2\text{O}_3$  appeared as smaller particles on the surface of the pre-deposited metal particles, resulting in increased particle fluctuations, as shown in Figure 1e–g.

The Te/Bi atomic ratio of all Bi $_2$ Te $_3$  films that sputtered with the same target and sputtering power was about ~1.5. The surface and cross section of  $Bi_2Te_3$  and  $M/Al_2O_3/Bi_2Te_3$ are given in Figure S2. Take Ag/Al $_2O_3/Bi_2$ Te $_3$  as an example, the surface of each layer is given in Figure 2a–c. Regardless of whether metal/oxide was previously deposited, there was no obvious difference in the surface morphology of the  $Bi_2Te_3$  film, the surface of which is selected as shown in Figure [2c](#page-2-0). The bottom-up  $Ag/Al_2O_3/Bi_2Te_3$  structure could be clearly seen from the cross section as shown in Figure [2d](#page-2-0). The thickness of the  $Bi<sub>2</sub>Te<sub>3</sub>$ film was about 300 nm, and the XRD pattern of  $Bi_2Te_3$  indicated that the obtained  $Bi_2Te_3$  is with good crystallinity as shown in Figure [2e](#page-2-0).

<span id="page-2-0"></span>

**Figure 2.** SEM image of (a)  $Ag/Al_2O_3$ , (b)  $Ag/Al_2O_3/Bi_2Te_3$ , and (c)  $Bi_2Te_3$ . (d) Cross section of Ag/Al2O3/Bi2Te3. (**e**) XRD pattern of Bi2Te3. Ag/Al2O3/Bi2Te<sup>3</sup> . (**e**) XRD pattern of Bi2Te<sup>3</sup> .

# *3.2. Carrier Transport Characteristics 3.2. Carrier Transport Characteristics*

All  $Bi_2Te_3$ -based films exhibit n-type conductivity, and the majority of carriers in the films are electrons as characterized by Hall measurements and shown in Figure [3a](#page-3-0)–c. Compared with the pure  $Bi_2Te_3$  film, the introduction of M (M = Cu, Ag, Au) in the film leads to a decrease in total electron concentration of the film as shown in Figure 3a. leads to a decrease in total electron concentration of the film as shown in Figure [3a](#page-3-0).

The role of introducing group IB metals in  $B_{12}Te_3$  can be summarized as follows: (i) In one way, one M atom should produce one electron compensating a hole. This process can be achieved by forming  $[MBiTe_2 + Bi_3Te_4]$ <sup>-</sup> through the alloying of  $Bi_2Te_3$  and M as shown in Figure [3g](#page-3-0) [\[23\]](#page-6-13). Generally, the diffusion, solid solution and alloying process of group IB metal in  $Bi_2Te_3$  can be modulated by heat treatment [\[23](#page-6-13)[–26\]](#page-6-14). Because the films in this study have not been annealed, the above effects, especially the alloying process (generate new phases), are weak. (ii) Another way is that the introduction of M atom could form interstitial  $M_i^+$  compensated by electrons. While the electronegativity (Pauling scale) of Cu, Ag, and Au atoms increases in turn (from 1.90, 1.93 to 2.54), the ability to form  $M_i^+$ decreases in turn [\[14\]](#page-6-4). Generally, since the space in the lattice is limited, atoms or cations with a smaller radius are more likely to form interstitial phases. The radius of Cu, Ag, and Au are 1.28 Å, 1.44 Å, and 1.44 Å, respectively. The radius of Cu<sup>+</sup>, Ag<sup>+</sup>, and Au<sup>+</sup> are 0.98 Å, 1.10 Å, and 1.10 Å, respectively [\[27\]](#page-6-15). In terms of the ability to form interstitial, the electron concentration of the Cu-introduced film should be less than that in the Ag-introduced film, which is confirmed in Figure [3a](#page-3-0). (iii) Since M (M = Cu, Ag, and Au) have fewer electrons in their outermost orbitals than Bi, doping them at the Sb-sites greatly increases the hole introduction of M  $\sim$ concentration and consequently reduces the electron concentration [\[19\]](#page-6-9).  $\mathcal{A}$  all  $\mathcal{B}$  and  $\mathcal{B}$  and the majority of carriers in the majority o which is committed in Figure 3a. (iii) once we two  $-$ c. Ag, and Au) have lewer electrons

<span id="page-3-0"></span>

**Figure 3.** Electrical properties of Bi<sub>2</sub>Te<sub>3</sub>-based films at 300 K. (a) Carrier concentration (*n*). (**b**) Carrier mobility ( $\mu$ ). (c) Electrical conductivity ( $\sigma$ ). Equilibrium band gap alignment of (**d**) Ag, Al<sub>2</sub>O<sub>3</sub> and Bi<sub>2</sub>Te<sub>3</sub>, (**e**) Cu, Al<sub>2</sub>O<sub>3</sub>, and Bi<sub>2</sub>Te<sub>3</sub>, (**f**) Au, Al<sub>2</sub>O<sub>3</sub>, and Bi<sub>2</sub>Te<sub>3</sub>. Behavior of electrons at the interface of  $(g)$  Metal/Bi<sub>2</sub>Te<sub>3</sub> and (**h**) Metal/Al<sub>2</sub>O<sub>3</sub>/Bi<sub>2</sub>Te<sub>3</sub>.

The coexistence of the above alloying, interstitial and doping process together determines the reduction of the electron concentration in the  $Bi<sub>2</sub>Te<sub>3</sub>$  film after the introduction of metal. Eventually, the electron concentration of the  $Bi_2Te_3$ ,  $Au/Bi_2Te_3$ ,  $Ag/Bi_2Te_3$ , and  $Cu/Bi<sub>2</sub>Te<sub>3</sub>$  film decreases sequentially. After the  $Al<sub>2</sub>O<sub>3</sub>$  layer was deposited to build a metal-insulator-semiconductor (MIS) interface, the electrons in the metal were blocked from entering Bi<sub>2</sub>Te<sub>3</sub> and some carriers may tunnel through the thin oxide layer from the metal into  $Bi<sub>2</sub>Te<sub>3</sub>$  as shown in Figure [3g](#page-3-0),h. Because there were unavoidable narrow holes in such thin  $Al_2O_3$  layer deposited by magnetron sputtering, there would still be some interfaces where the metal was in direct contact with  $Bi<sub>2</sub>Te<sub>3</sub>$ . The above-mentioned combined effect made the carrier concentration of the film further decrease after the  $Al_2O_3$ layer was introduced.

As the electron concentration decreased after metal or oxide was introduced, the scattering between electrons was weakened and the mobility of the film increased. On the other hand, the introduction of a metal-semiconductor (MS) interface or an MIS interface would lead to the reduction of the mobility which was closely related to the size and distribution of the metal particles and the surface  $Al_2O_3$  that covers them. The interfaces and the corresponding electronic transport processes are illustrated in Figure [3d](#page-3-0)–f. The above combined effect makes the total electrical mobility and conductivity of the films other than  $Ag/Bi<sub>2</sub>Te<sub>3</sub>$  increase while compared to the pure  $Bi<sub>2</sub>Te<sub>3</sub>$ , which may be related to the Ohmic contact of the Ag-Bi<sub>2</sub>Te<sub>3</sub> interface and Ag particle with relatively high height (thickness). In addition to filtering out low-energy electrons based on the interface barrier, an additional oxide layer was deposited to control the tunneling electron concentration. Through the above dual effects, the concentration and average energy of electrons can be adjusted.

#### *3.3. Thermoelectric Properties*

The Seebeck coefficient is closely related to the carrier concentration and its energy distribution, and the contribution of low-energy carriers to the Seebeck coefficient is negative [\[28\]](#page-6-16). The measured Seebeck coefficient of  $Bi<sub>2</sub>Te<sub>3</sub>$ -based film is presented in Figure [4a](#page-4-0). It can be seen from Figure [4a](#page-4-0) that the Seebeck coefficients of the film with Cu and Au are lower than the pure  $Bi<sub>2</sub>Te<sub>3</sub>$ , which may be related to the relatively high interface barrier that filters out some high-energy electrons. The deposited  $Al_2O_3$  layer allowed tunneling electrons to pass through, which would reduce the concentration of high-energy tunneling electrons to pass through, which would reduce the concentration of electrons in the film, and ultimately reduce the Seebeck coefficient.

<span id="page-4-0"></span>

Figure 4. Thermoelectric properties of Bi<sub>2</sub>Te<sub>3</sub>-based films at 300 K. (a) Seebeck coefficient (S). (b) Seebeck coefficient as a function of carrier concentration (Pisarenko plot). Dashed lines represent theoretical fits for  $m^*$  = 0.3  $m_0$ , 2.5  $m_0$ , 3  $m_0$ , 4  $m_0$  and 7  $m_0$  based on Equations (1)–(3).  $m_0$  is mass of free electron. (**c**) Power factor  $(S^2\sigma)$ .

For a material with a single parabolic band, the Seebeck coefficient, DOS effective For a material with a single parabolic band, the Seebeck coefficient, DOS effective mass of carriers (*m*\*) and Lorenz number (*L*) can be written as [22,29] mass of carriers (*m*\*) and Lorenz number (*L*) can be written as [\[22](#page-6-12)[,29\]](#page-6-17)

$$
S = \frac{K_B}{e} \left( \frac{(5/2 + \lambda) F_{3/2 + \lambda}(\eta)}{(3/2 + \lambda) F_{1/2 + \lambda}(\eta)} - \eta \right)
$$
(1)

$$
m^* = \frac{h^2}{2K_b T} \left(\frac{n}{4\pi F_{1/2}(\eta)}\right)^{2/3} \tag{2}
$$

$$
F_i(\eta) = \int_0^\infty \frac{x^i dx}{1 + \exp(x - \eta)}
$$
(3)

$$
L = \left(\frac{k_B}{e}\right)^2 \left\{ \frac{(\lambda + 7/2)F_{\lambda + 5/2}(\eta)}{(\lambda + 7/2)F_{\lambda + 1/2}(\eta)} - \frac{(\lambda + 5/2)F_{\lambda + 3/2}(\eta)^2}{(\lambda + 3/2)F_{\lambda + 1/2}(\eta)} \right\}
$$
(4)  

$$
\kappa_e = LT\sigma
$$

$$
\kappa_{\rm e} = LT\sigma\tag{5}
$$

 $Boltzmann constant, Lorenz number, and absolute temperature, respectively.  $\eta$  is the$ reduced Fermi energy ( $E_F/k_BT$ ),  $F_i$  is the fermi integral of the order of x. Acoustic phonon scattering ( $\gamma$  =  $-1/2$ ) has been assumed as the main carrier scattering mechanism at room temperature. The corresponding calculation results at 300 K are listed in Table 1. In order to compare the effect of interface on the Seebeck coefficient of Bi<sub>2</sub>Te<sub>3</sub> at room temperature, Pisarenko plot is applied as shown in Figure 4b. where  $e$ ,  $m^*$ ,  $h$ ,  $k_B$ ,  $L$ , and  $T$  are the electronic charge, effective mass, Planck's constant,

der to compare the effect of interface on the Seebeck coefficient of Bi2Te3 at room tem-**Table 1.** Thermoelectric parameters of Bi<sub>2</sub>Te<sub>3</sub>-based films at 300 K.

<span id="page-4-1"></span>

Sample		CВ	CAB	SB	<b>SAB</b>	GB	GAB
$m^*/m_0$	6.38	2.56	0.26	3.80	0.30	3.92	3.12
$L(V^2 \cdot K^{-2})$	$2.04\times10^{-8}$	$2.08\times10^{-8}$	$2.12 \times 10^{-8}$	$2.01 \times 10^{-8}$	$2.05 \times 10^{-8}$	$2.09 \times 10^{-8}$	$2.14 \times 10^{-8}$
$\kappa_e$ (W·m <sup>-1</sup> ·K <sup>-1</sup> )	0.37	0.40	0.00	0.18	0.56	0.47	0.72

Figure 4c. Compared with pure Bi2Te3, the power factor of the film introduced with met-After the metal was introduced into Bi<sub>2</sub>Te<sub>3</sub> film, the  $m^*$  of the film was reduced, and it was further reduced after the oxide layer was introduced as shown in Table [1.](#page-4-1) However, which is 1.75 which is 1.75 metal is 1.75 metal in Table 1. However, when compared with Cu-introduced and Ag-introduced films, the effective mass change in the Au-introduced film was small, which was closely related to the carrier behavior<br>
in the Au-introduced film was small, which was closely related to the carrier behavior as analyzed before. The power factor of  $Bi<sub>2</sub>Te<sub>3</sub>$ -based film at 300 K is given in Figure [4c](#page-4-0). Compared with pure  $Bi<sub>2</sub>Te<sub>3</sub>$ , the power factor of the film introduced with metal and oxide

is increased, which benefits from the effect of metals and the MIS interface. As a result, the power factor of the Cu/Al<sub>2</sub>O<sub>3</sub>/Bi<sub>2</sub>Te<sub>3</sub> film is 6.5  $\mu$ W·cm<sup>-1</sup>·K<sup>-2</sup>, which is 1.75 times that of a single  $Bi_2Te_3$  film. In addition, the corresponding electronic thermal conductivity calculated according to Equation (5) is given in Table [1.](#page-4-1)

Although the introduction of  $Cu/Al<sub>2</sub>O<sub>3</sub>$  leads to an increase in the electronic thermal conductivity of the film, the smaller Cu particles result in a higher interface density (Figure [1b](#page-1-0)), which could scatter phonons more strongly and make the lattice thermal conductivity lower [\[30\]](#page-6-18). In addition to scattering phonons at the interface to reduce the thermal conductivity, it is particularly important to use the interface to optimize the thermoelectric power factor to improve the overall performance of the film.

### **4. Conclusions**

In summary, metal (Cu, Ag, Au)/Al2O3/Bi2Te<sup>3</sup> heterostructures have been fabricated to improve the thermoelectric properties. By constructing the metal-semiconductor and metal-insulator-semiconductor interface, using the filter carrier effect or controlling the tunneling electrons, it is possible to coordinately control the carrier concentration and mobility, and finally optimize the thermoelectric power factor. The power factor of the Cu/Al<sub>2</sub>O<sub>3</sub>/Bi<sub>2</sub>Te<sub>3</sub> heterostructure film is 6.5  $\mu$ W·cm<sup>-1</sup>·K<sup>-2</sup>, which is 1.75 times that of a single  $Bi_2Te_3$  film. Future work will focus on optimizing the metal particle size, oxide layer thickness, and annealing process to further optimize the thermoelectric performance. Related works are still ongoing.

**Supplementary Materials:** The following are available online at [https://www.mdpi.com/article/](https://www.mdpi.com/article/10.3390/mi12050480/s1) [10.3390/mi12050480/s1,](https://www.mdpi.com/article/10.3390/mi12050480/s1) Figure S1: AFM step profiler of (**a**) Cu and (**d**) Au. Figure S2: Surface of (**a**)  $Bi_2Te_3$ , (**b**)  $Cu/Al_2O_3/Bi_2Te_3$ , (**c**)  $Ag/Al_2O_3/Bi_2Te_3$ , (**d**)  $Au/Al_2O_3/Bi_2Te_3$ . Cross section of (**e**) Bi2Te<sup>3</sup> , (**f**) Cu/Al2O3/Bi2Te<sup>3</sup> , (**g**) Ag/Al2O3/Bi2Te<sup>3</sup> , (**h**) Au/Al2O3/Bi2Te<sup>3</sup> .

**Author Contributions:** Methodology, formal analysis, writing—original draft preparation, Z.W.; investigation, data curation, S.Z., Z.L. and C.L.; Supervision and funding acquisition, Z.H. All authors have read and agreed to the published version of the manuscript.

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**Conflicts of Interest:** The authors declare no conflict of interest.

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